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Appl. No. 09/844,175

Response to Office Action malled 9/28/2005

In the Claims

Claims 1-30 are canceled.

31. [Previously Presented] A removable electrical interconnect apparatus for

removably engaging electrically conductive pads on semiconductor substrates having

integrated circuitry fabricated therein, the apparatus comprising:

an apparatus substrate; and

an engagement probe projecting from the apparatus substrate to engage a single

conductive pad on a semiconductor substrate having integrated circuitry formed in the

semiconductor substrate, the engagement probe having an outer surface comprising an

apex in the form of a knife-edge line and comprising semiconductor material and

configured to removably penetrate a single conductive pad of the semiconductor substrate

comprising integrated circuitry and to removably penetrate another single conductive pad

of another semiconductor substrate also comprising integrated circuitry.

32. [Previously Presented] The removable electrical interconnect apparatus of

claim 31 wherein the engagement probe is formed on a projection from the apparatus

substrate.

33. [Original] The removable electrical interconnect apparatus of claim 31

wherein the knife-edge line projects from a penetration stop plane.

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- 34. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the knife-edge line projects from a penetration stop plane, the knife-edge line having a tip and having a base at the penetration stop plane, the tip being a distance from the penetration stop plane of about one-half the thickness of conductive pads which the apparatus is adapted to engage.
- 35. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the engagement probe is formed on a projection from the apparatus substrate, the knife-edge line projecting from a penetration stop plane on the projection.
- 36. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the engagement probe is formed on a projection from the apparatus substrate, the knife-edge line projects from a penetration stop plane on the projection, the knife-edge line having a tip and having a base at the penetration stop plane, the tip being a distance from the penetration stop plane of about one-half the thickness of conductive pads which the apparatus is adapted to engage.
- 37. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein outermost portions of the apex comprise a first electrically conductive material, and wherein the conductive pads for which the apparatus is adapted to engage have outermost portions comprising a second electrically conductive material; the first and second electrically conductive materials being different.

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- 38. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the engagement probe comprises material of a bulk semiconductor substrate.
- 39. [Original] The removable electrical interconnect apparatus of claim 31 wherein the knife-edge line includes an outer conductive layer.
- 40. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the outer surface includes plural knife-edge lines configured to engage the single conductive pads.
- 41. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the engagement probe is formed from a semiconductor substrate and the outer surface includes plural knife-edge lines configured to engage the single conductive pads.
- 42. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the engagement probe is formed from a semiconductor substrate and the outer surface includes plural knife-edge lines configured to engage the single conductive pads and the knife-edge lines include outer conductive layers.

Claims 43-53 are canceled.

54. [Currently Amended] A removable engagement probe having an outer surface comprising an apex in the form of a knife-edge line and comprising semiconductor material and sized and positioned to penetrate a single conductive pad; and wherein the knife-edge line projects from a penetration stop plane; and wherein the knife-edge line is formed on a projection from a substrate.

- 55. Cancel.
- 56. [Currently Amended] The removable engagement probe of claim 54 wherein the outer surface comprises a plurality of apexes having respective tips and bases, and the penetration stop plane is intermediate the bases and substantially parallel to a surface of [[a]] the substrate.
- 57. [Previously Presented] The removable engagement probe of claim 54 wherein the knife-edge line has a tip and has a base at the penetration stop plane, the tip being a distance from the penetration stop plane of about one-half the thickness of the conductive pad which the apparatus is adapted to engage.

58. [Currently Amended] The removable engagement probe of claim 54 wherein the knife-edge line is formed on a projection from a substrate and projects from the penetration stop plane on the projection.

59. [Currently Amended] The removable engagement probe of claim 54 wherein the knife-edge line is formed on a projection from a substrate and projects from the penetration stop plane on the projection, the knife-edge line having a tip and having a base at the penetration stop plane, the tip being a distance from the penetration stop plane of about one-half the thickness of the conductive pad which the apparatus is adapted to engage.

- 60. [Previously Presented] The removable engagement probe of claim 54 wherein outermost portions of the apex comprise a first electrically conductive material, and wherein the conductive pad for which the probe is adapted to engage has outermost portions comprising a second electrically conductive material; the first and second electrically conductive materials being different.
- 61. [Previously Presented] The removable engagement probe of claim 54 wherein the probe comprises material of a bulk semiconductor substrate.

- 62. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the knife-edge line is sized and positioned to extend elevationally above an uppermost surface of the apparatus substrate.
- 63. [Previously Presented] The removable electrical interconnect apparatus of claim 32 wherein the projection includes a surface substantially parallel to a surface of the apparatus substrate.
- 64. [Currently Amended] The removable engagement probe of claim 54 wherein the knife-edge line projects elevationally above an uppermost surface of a substrate the projection which defines the penetration stop plane.
- 65. [Currently Amended] The removable engagement probe of claim [[55]] <u>54</u> wherein the projection has a surface substantially parallel to a surface of [[a]] <u>the</u> substrate and <u>which</u> <u>the surface of the projection</u> defines the penetration stop plane.
 - 66. Canceled.
- 67. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the apparatus substrate comprises semiconductor material.

68. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the apparatus substrate comprises semiconductor material and the engagement probe comprises semiconductor material of the apparatus substrate.

69. [Previously Presented] The removable engagement probe of claim 54 wherein the engagement probe comprises semiconductor material.

70. [Previously Presented] The removable engagement probe of claim 54 wherein the engagement probe comprises semiconductor material formed from a semiconductor substrate.

Claims 71-74 are canceled.

75. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the apex comprises a solid mass of material devoid of any void space.

76. [Previously Presented] The removable engagement probe of claim 54 wherein the apex comprises a solid mass of material devoid of any void space.

77. [Currently Amended] An electrical system comprising:

a first electrically conductive pad on a first semiconductor substrate comprising

integrated circuitry formed using the first semiconductor substrate;

a second electrically conductive pad on a second semiconductor substrate

comprising integrated circuitry formed using the second semiconductor substrate; and

a removable electrical interconnect apparatus for removably engaging configured

to removably engage the first and second electrically conductive pads, the apparatus

comprising:

an apparatus substrate; and

an engagement probe projecting from the apparatus substrate to engage the

first electrically conductive pad, the engagement probe having an outer surface and

comprising an apex in the form of a knife-edge line and comprising wherein the apex

comprises semiconductor material and configured to removably engage the first electrically

conductive pad and to removably engage the second electrically conductive pad.

78. [Previously Presented] The electrical system of claim 77 wherein the apex

is configured to penetrate the first and the second electrically conductive pads.

79. [Currently Amended]

An electrical system comprising:

a single conductive pad;

a removable engagement probe having an outer surface comprising an apex in the form of a knife-edge line and comprising semiconductor material and sized and positioned to engage the single conductive pad; and

wherein the knife-edge line projects from a penetration stop plane.

- 80. [Previously Presented] The electrical system of claim 79 wherein the apex is configured to penetrate the single conductive pad.
- 81. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the apex in the form of the knife-edge line comprises a polyhedron.
- 82. [Previously Presented] The removable electrical interconnect apparatus of claim 31 wherein the apex in the form of the knife-edge line comprises a triangular prism.
- 83. [Previously Presented] The removable engagement probe of claim 54 wherein the apex in the form of the knife-edge line comprises a polyhedron.
- 84. [Previously Presented] The removable engagement probe of claim 54 wherein the apex in the form of the knife-edge line comprises a triangular prism.

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- 85. [Previously Presented] The electrical system of claim 77 wherein the apex in the form of the knife-edge line comprises a polyhedron.
- 86. [Previously Presented] The electrical system of claim 77 wherein the apex in the form of the knife-edge line comprises a triangular prism.
- 87. [Previously Presented] The electrical system of claim 79 wherein the apex in the form of the knife-edge line comprises a polyhedron.
- 88. [Previously Presented] The electrical system of claim 79 wherein the apex in the form of the knife-edge line comprises a triangular prism.
- 89. [New] A removable engagement probe having an outer surface comprising an apex in the form of a knife-edge line and comprising semiconductor material and sized and positioned to penetrate a single conductive pad;

wherein the knife-edge line projects from a penetration stop plane; and wherein the outer surface comprises a plurality of apexes having respective tips and

bases, and the penetration stop plane is intermediate the bases and substantially parallel

to a surface of a substrate.

90. [New] A removable engagement probe having an outer surface comprising an apex in the form of a knife-edge line and comprising semiconductor material and sized and positioned to penetrate a single conductive pad;

wherein the knife-edge line projects from a penetration stop plane; and wherein the knife-edge line has a tip and has a base at the penetration stop plane, the tip being a distance from the penetration stop plane of about one-half the thickness of the conductive pad which the apparatus is adapted to engage.

91. [New] A removable engagement probe having an outer surface comprising an apex in the form of a knife-edge line and comprising semiconductor material and sized and positioned to penetrate a single conductive pad;

wherein the knife-edge line projects from a penetration stop plane; and wherein outermost portions of the apex comprise a first electrically conductive material, and wherein the conductive pad for which the probe is adapted to engage has outermost portions comprising a second electrically conductive material, the first and second electrically conductive materials being different.